

V085413597  
EL979955752

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. ....08/846,671  
Filing Date .....April 30, 1997  
Inventor .....Kei-Yu Ko  
Assignee .....Micron Technology, Inc.  
Group Art Unit .....1763  
Examiner .....George A. Goudreau  
Attorney Docket No. ....MI22-2041  
Title: Undoped Silicon Dioxide as Etch Stop for Selective Etch of Doped Silicon  
Dioxide

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with  
37 CFR §1.56. Copies of the cited art are included. No admission is made  
regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 6-6-03

By:   
Mark S. Matkin  
Reg. No. 32,268

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2041		SERIAL NO. 08/846,671		
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Kei-Yu Ko				
				FILING DATE April 30, 1997		GROUP 1763		
U.S. PATENT DOCUMENTS								
Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate	
	AA	5,430,328	07/04/95	Hsue				
	AB	6,065,481	05/23/00	Fayfield et al.				
	AC	6,362,109	03/26/02	Kim et al.				
	AD	6,372,605 B1	04/16/02	Kuehne et al.				
	AE							
	AF							
	AG							
	AH							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AI	6146/91	27.08.92	Japan (Nakano)			X	
	AJ	6-69166	11.03.94	Japan (Tokuhiko)			X	
	AK	8-181121	12.07.96	Japan (Fujita)			X	
	AL	8-250449	27.09.96	Japan (Tetsuo)			X	
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AM							
	AN							
	AO							
EXAMINER		DATE CONSIDERED						
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								